Metasurface Flat Optics



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Capasso Group Harvard School of Engineering and Applied Sciences

Vision for Flat Optics

F. Capasso, Nanophotonics, 6 953 (2018)

- Planar technology is central to IC technology: Technology platform
- Same foundries will manufacture camera sensor and lenses using same technology (deep-UV stepper)
- Single phase mask (lithographic level) generates the metaoptical component
- > Metasurfaces that give arbitrary control of the phase, amplitude and polarizations of light
- > Our goals:

CMOS compatible flat optics platform for high volume markets:

cameras (cell phone camera modules, laptops, automotive, biometrics), displays, wearable optics (augmented reality). TiO2 : high quality material platform for visible Amorphous Si: same for near IR Fused Silica (SiO₂)

Example: lenses in cell phone camera modules will be replaced by metalenses fabricated by deep UV steppers (same foundry that makes the sensor chip): thinner, easier fabrication and alignment

- Flat Optics for a wide range of optical components (lenses, holograms, polarizers, phase plates, etc.) machine vision, biomed imaging, scientific applications (OCT), drones, polarimetry laser lithography, OEM markets
- **Multifunctionality:** single flat optical components replaces multiple standard components with attendant reduction of system complexity and footprint

Why Lenses are thick ? Can we make a flat lens?



- All lenses suffer from distortions in the way they focus
- Focal point is blurred by aberrations (spherical, astigmatism, coma, etc.)
- Can be corrected by using multiple lenses, which however makes the optics much thicker, bulky and heavier

Lens becomes more demanding

Conventional lens manufacturing: grinding, polishing and plastic molding



- Largan Precision company (major cell phone lens supplier) produces ~ 17 billions plastic lens modules
- These lenses are for various applications: cellphone/NB lenses, webcam lenses, car and camera lenses etc.



Can we make a flat lens with no aberrations?



- All rays focused to the same point? i.e. diffraction limited.
- Two challenges: doing it first for "single" wavelength and then for a broad spectrum?
- By structuring with nanotechnology a planar surface so that all rays converge to the same focus

The surface is nanostructured: METASURFACE



Metasurfaces: complete wavefront control

Huygens-Fresnel Principle



- Straight-Forward Fabrication
 - One mask level, cost effective
- Compact
 - Light weight, capability to be vertically integrated
- Unprecedented Control of Dispersion
- Overcome Limitations of Conventional Optics
 - Aberrations, multifunctionality

Metasurface: Manipulating phase using nanostructures

• Control Amplitude, phase, polarization and wavenumber of light

$$\vec{E} = A \cdot \exp^{i(k_z \cdot z + \varphi)} \hat{y}$$



Fresnel Optics vs Metasurface Based Optics



A single digital pattern (one mask level) can create an arbitrary analog phase profile

Unique properties of metalens

- Lithography-based Fabrication: nano-meter precision with high throughput
- Flat and Compact: compatible with wafer packing



- Tunable dispersion:
 - Refractive lens: dispersion is given by glass material



 Metalens: Tailorable through nanostructures



General design process

- Flow of convention metasurface design
 - 1. Target phase profiles from analytical solution or raytracing

2. Build a nanostructure library by parameter sweep

- Most cases are related to geometric optics
- Hologram is an exception, which requires diffraction calculation to obtain target phase profile.

• Solving Maxwell's equations by a simulation software

3. Matching target phase with nanostructure phase for each spatial coordinate

 Choosing elements from the library based on a figure of merit

General principle

Light rays propagate to the direction where there are in-phase.



Example: Lens



More complicated cases

Immersion metalens



ReF: Chen, W. T. et al. Immersion Meta-Lenses at Visible Wavelengths for Nanoscale Imaging. Nano Lett. 17, 3188-3194 (2017)

Doublet metalens



- Raytracing software (Zemax: OpticsStudio, Synopsys: CodeV etc):
- Binary 2 surface in OpticsStudio

Taylor expansion of $\varphi(x)$:

Only considers even terms, because lens phase profile is symmetric



The software tunes a_n to minimize figure of merit

Normalization constant

Ref: Groever, B., Chen, W. T. & Capasso, F. Meta-Lens Doublet in the Visible Region. Nano Lett. 17, 4902-4907 (2017).

Ref: Arbabi, A. et al. Miniature optical planar camera based on a wide-angle metasurface doublet corrected for monochromatic aberrations. Nat. Commun. 7, 13682 (2016).

Available simulation packages

- Simulation packages (solving full Maxwell's Equations) CST : https://www.cst.com/ COMSOL: <u>https://www.comsol.com/</u> Lumerical: https://www.lumerical.com/
- Our codes are developed based on Lumerical. However, the simulation principle is valid using other simulation packages.
- Other useful information:
 Nano hub: https://papobub.org/

Nano-hub: <u>https://nanohub.org/courses/NPM</u>



EM lab: On Youtube, search CEM lectures

Choose element based on merit functions

Target phase



Repeat this for all coordinates to choose proper structure

Structure phase

Chromatic response of metalenses

Polarization-insensitive chromatic metalens

Polarization-sensitive achromatic metalens



Metalens Fabrication Process: ALD & Ebeam Lith.

Current fabrication approach





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TiO2 Metasurfaces by Atomic Layer Deposition:

Completely transparent in the visible; Negligible roughness, Vertical walls



R.C. Devlin, *et al. Proc. Nat. Acad. Sci* .**113**, 10473 (2016) E. Shkondin, et al. *J. Vac. Sci. Technol* **34**, 031605 (2016).

Diffraction Limited High NA Metalenses

M. Khorasaninejad et al. Nano Lett., 16, 7229 (2016).



Ø = 2 mm; f= 800µm NA= 0.8

Focusing efficiency: 60% to 80 % depending For NA in 0.8 to 0.6 range



18

Experimental Setup for Point Spread Function Measurement







F. Aieta, et al. Science, (2015).



Controlling chromatic dispersion is critical in

- Maintaining the same functionality over a bandwidth (important for imaging applications)
- Implementing different functionalities at different wavelengths (spectral multifunctionalities)

Effect of chromatic aberration

Complexity of Achromatic Lens Design

Conventional approaches for reducing chromatic aberration



 Conventional design approaches (doublets for example)
 Under thin lens approximation, lack of clear physical insights

$$\begin{cases} \phi_1 + \phi_2 = \phi_{total} \\ \frac{\phi_1}{V_1} + \frac{\phi_2}{V_2} = 0 \\ \cdot \text{ Lens power } \phi = \frac{1}{f} \text{ Abbe number } V = \frac{n_{\text{somm}} - 1}{n_{\text{ascmm}} - n_{\text{sofmm}}} \end{cases}$$



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Achromatic metalens

• To realize achromatic focusing, one needs to manipulate wavepackets in both spatial and time domains.



$$\varphi(r,\omega) = \varphi(r,\omega_d) + \frac{\partial \varphi(r,\omega)}{\partial \omega} \bigg|_{\omega=\omega_d} (\omega-\omega_d) + \frac{1}{2} \left| \frac{\partial^2 \varphi(r,\omega)}{\partial \omega^2} \right|_{\omega=\omega_d} (\omega-\omega_d)^2 + \dots$$

gives lens function
Group delay (GD): time delay Group delay dispersion (GDD): temporal width
Ref: W.T. Chen, and E. Capasso et al. *Nature Nanotechnology* **13** 220–226 (2018)

Broadband Achromatic Metalenses

W-T Chen et al. Nature Nanotechnology Jan 1 (2018) doi:10.1038/s41565-017-0034-6



Requirement for GD and GDD

$$\varphi(r,\omega) = -\frac{\omega}{c}(\sqrt{r^2 + F^2} - F), \quad F \to F(\omega) = k\omega^n \quad (k \text{ is a constant})$$

Achromatic n = 0, Conventional diffractive n =1, Anomalous diffractive n =2, Refractive n = -1



• NA = 0.2, F = 64 μm at 530 nm

Polarization-insensitive lens consisting of anisotropic nanostructures



REF: W-T Chen et al Nature Communications In press



Full lens simulation

- NA = 0.55, Dia = 6.5 μm
- Layout: Achromatic and polarization-insensitive metalens



• FDTD simulation



Chromatiic (Without dispersion Engineering)



Polarization-insensitive and Achromatic Metalens





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White light focusing





Phase profile of metacorrector





Hybrid Metalens Design

Ray-tracing simulation





• Spherical lens + metacorrector (Dia = 1.5 mm, NA = 0.075)



Inverse design of large-area multi-wavelength (RGB) metalenses



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Virtual Reality platform



Meta-eyepiece X laser-illuminated micro-LCD



RGB-achromatic

Wide Color gamut







VR movie: a running cat



• Frame refresh rate: 60Hz

Metalens Doublet to correct monochromatic aberrations (spherical, coma, astigmatism and field curvature)

> Doublet metalens: NA = 0.45, FOV = 50°



Aperture metalens



- Ray-tracing diagrams:
 - Singlet metalens



Doublet metalens



B. Grover et al. Nano Lett., DOI: 10.1021/acs.nanolett.7b01888 June 29, 2017

Focal spot and imaging

> Lens test set-up:



Imaging set-up:



Scale bar: 11 µm

Metalens for High Resolution Bronchoscopes

Hamid Pahlevani et al. Nature Photonics https://doi.org/10.1038/s41566-018-0224-2

Collaboration with Mass General Hospital, Prof. Melissa Suter




Endoscopic imaging using metalens catheter



epi: epithelium; bm: basement membrane; car: cartilage ves: blood vessels; alv: alveolar; gp: glandular patterns

Fabrication of metalenses with semiconductor technology

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Fabrication with deep-UV (DUV) projection lithography (Eused silica papostructures etched into a fused silica wafe

(Fused silica nanostructures etched into a fused silica wafer)



Focusing profile along optic axis

VE RI TAS

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Fabrication process

Fabrication process (on 4-inch SiO₂ wafer)

Projection lithography (same technique used in chip manufacturing)



Large diameter (10cm) metalens: Comparison with Similar Optical Power Refractive Lens





https://pubs.acs.org/doi/abs/10.1021/acsnano.3c09462

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Focusing Quality Measurement



- Apparent reticle quality difference between inner/outer fields.
- Low-quality reticle did not resolve small-diameter nanopillars.
- Results in low diffraction efficiency at outer region.



-80

- Total metalens focusing efficiency: 40.4%
- Central area focusing efficiency: 63.1 %

This 100 mm diameter metalens has 19 Billion glass nanopillars

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80

60

z [um]

Meta-imaging the Heavens



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> North America Nebula (NGC7000), Cambridge, MA



Metalenz Inc.: spin-off (2016) from the Capasso group



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Enabling the future of metaoptics in the semiconductor foundry



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::: metalenz



Intensity on CIS

			_
Metrics	4P	WLO	metalenz
Design	4P	2P	1M
Track Length (mm)	3.5	3.1	3.0
Module MTF 0F/0.7F (%) @nyq/2	36/26	15/10	38/32
RI (%)	40	20	70
Total intensity (a.u.)	1	0.75	2
Distortion (%)	2	17	20
Chief ray angle (deg)	30	30	0

Relative Illumination (RI) represents the combined effects of vignetting and roll-off % of illumination at any point on the sensor, normalized to the with maximum illumination







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Metalenz and STMicroelectronics deliver world's first optical metasurface technology for consumer electronics devices June 09, 2022 STMicroelectronics N.V.



Metalenz co-founder Rob Devlin holds up a 12-inch wafer of printed metalenses

Forbes Jun 8, 2022 World's First Printable Optical Metasurface For Vision, 3D Sensing, LIDAR Now Shipping In Consumer Products John Koetsier, Senior Contributor High Volume Semiconductor Foundry-Based Lens Manufacturing



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- Metalenz announced a partnership with UMC (major foundry) for high-volume manufacturing of optical lenses using commercial semiconductor processing platforms. UMC is amongst the largest semiconductor foundries in the world.
- The partnership enables high-volume manufacturing of optical lenses for 3D imaging in applications ranging from smartphones and laptops to IoT (Internet of Things) and automotive sensing.

https://www.forbes.com/sites/sabbirrangwala/2023/07/05/metalenz-pioneers-high-volumesemiconductor-foundry-based-lens-manufacturing/?sh=f5e36d423bde Capasso Group



Extreme Ultraviolet Metalenses







Hana Hampel Martin Schultze

M. Ossiander et al., Science 380, 59–63 (2023)



Extreme ultraviolet radiation

- Why focus XUV?
 - manipulate and observe electron motion in atoms and molecules
 - nonlinear attosecond dynamics
 - XUV semiconductor lithography
- Goal of this project: design and test a transmitting XUV-focusing metaoptic
- XUV Sources:
 - synchrotrons
 - free electron lasers
 - tin-droplets plasma
 - high harmonic generation







Source: DOI: 10.1126/science.1189401 Source: https://www.cecam.org/workshop-1552.html

High harmonic generation: spectrum



EUV Material Properties

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n_{material} < n_{vacuum} → vacuum suddenly guiding

k_{material} > 0 → thin device

 \rightarrow thin / no substrate



But is it worth it?



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EUV Metasurface Fabrication

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back side spin coat MLA membrane area RIE-10, Bosch etch **BHF** wet etched





Focussing of XUV radiation

• transmitting metaoptics

- wavelength-scale structures made of Si
- optimized for 50 nm radiation:



Hana Hampel Martin Schultze



Sample preparation: Maryna Meretska Soon Wei Daniel Lim







Measurement



Multifunctional Meta-Optics



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Miniature spectrometers

- Recently freeform optics have emerged as a potential solution these are off-axis, non-rotationally symmetric components
- Examples include e.g. toroidal gratings, aspherical off-axis mirrors
- Difficult to fabricate and generally bulky/expensive



Diamond machining of off-axis mirrors





Rotationally symmetric, non-standard shapes





Other complex shapes and concave/toroidal gratings

Meta-spectrometers: Making good use of Chromatic Effect



- Off-axis metalens has better spectral resolution because of angular and longitudinal dispersions.
- Off-axis metalens suffers two major aberrations (field curvature and astigmatism), which limite its spectral resolution and range in a narrow bandwidth.

Aberration-corrected metalens spectrometer

 Flat and perpendicular focal plane realized by dispersion-engineered metalens



 Coupled TiO₂ waveguide for fine tuning dispersion



> Measured focal spots (FWHM ~ 56 μ m)



488 nm

Dispersion engineered metalens







Without dispersion engineering

532 nm







- Metalens dispersion and spectral resolution
- Dispersion

0.8



Spectral resolution

(Reciprocal linear dispersion × Focal spot size)



~ 0.73 nm spectral resolution from 470 to 660 nm in the visible

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Light is subject to the diffraction limit.

There is a smallest angle or volume it can be localized in.

There is no diffraction limit for dark.

Singularities can be arbitrarily localized.

Structuring Dark via Phase Singularities



Our Recipe for sheet singularities: maximize phase gradient orthogonal to desired sheet!



Point Singularities



Inverse design of point singularities



- Design strategy:
 - Step 1: Produce point singularities at each position.
 - Step 2: Equalize optical environment across positions.

S. D. Lim, J-S. Park, D. Kazakov, C. M Spaegele, A. H Dorrah, M. L Meretska, and F. Capasso Nature Communications, 14, 3237 (2023.



Experimental realization

- Phase-only metasurface using TiO₂ nanopillars on SiO₂.
- Protocol [1]:
 - 1. Electron beam lithography to produce nano-holes.
 - 2. Backfill of holes with TiO₂ using atomic layer deposition.
 - 3. Etch back of excess TiO_2 with reactive ion etching.
 - 4. Deposition of gold aperture mask to eliminate stray light.





[1] R. C. Devlin, M. Khorasaninejad, W. T. Chen, J. Oh, and F. Capasso, Broadband high-efficiency dielectric metasurfaces for the visible spectrum, *Proc. Natl. Acad. Sci. USA* **113**, 10473–10478 (2016).



Experimental results





C.M. Spaegele, M. Tamagnone, S.W.D. Lim, M. Ossiander, M.L. Meretska & F. Capasso. Science Advances 9, 24 (2023)



Sheet phase singularities



1D cut profile Device phase map [rad] **3D Isosurface** b С а Propagation dir. 400 띰 -20 3π/2 ¹is -30 g -40 -200 10 ٠ Sheet singularity with heart-shaped cross-[m] 5 0 -50 Singularity she Vortex beam ر سا ر -60 1e4 section designed using phase gradient -Singularity shee -5 Vortex beam maximization and fabricated. -10 π/2 ≱ 1e0-Δ 200 -15 For 532 nm wavelength. • -20 9.96 1e-2 6 9.98 10.00 [mm] 10.02 [0.04 - 20 - 10 Metasurface platform: TiO₂ nanopillars 1e-4 -12 -10 -8 -6 -4 x [um] 400 -0 -2 z [mm] -400 -200 200 0 x [um] 400 x [um] on SiO₂ Sim. intensity [dB] d Exp. intensity [dB] f GS sim. intensity [dB] е Fidelity and contrast attained is superior to ٠ 15 20 20 that obtained using the Gerchberg-Saxton -10 10 -10 10 (GS) algorithm. -15 j (um] -15 -15 -20 -20 -20 -25 -25 -25 Full metasurface -10 Superpixel zoom in -30 -30 100 µm 35 35 -20 -10 0 10 20 -20 -15 -10 -5 0 5 10 15 20 -20 -30 -20 -10 0 x [um] 10 20 -30 x [um] -----1D cut profile x [um] Sim. phase [rad] h Exp. retrieved phase [rad] i. GS sim. phase [rad] [m -10 1000 nm

Soon Wei Daniel Lim, Joon-Suh Park, Maryna L. Meretska, Ahmed H. Dorrah, and F. Capasso., Nature Communications, 12, 4190 (2021)



3D singularity sheet structure flythrough



- Close correspondence between simulated and experimental intensity and phase profiles as a function of axial position (z).
- This sheet singularity is unstable with propagation, like fractional topological charge vortices [1-2] and high-order vortices.
 - But some highly symmetric sheet singularities are stable: e.g., 1D diffraction fringes, Bessel beam nodes.



Soon Wei Daniel Lim, Joon-Suh Park, Maryna L. Meretska, Ahmed H. Dorrah, and F. Capasso., Nature Communications, 12, 4190 (2021)



Structuring dark around obstacles





F. Capasso, Nanophotonics, 6 953 (2018)

- Metasurfaces provide arbitrary control of the wavefront (phase, amplitude and polarization)
- > Metasurfaces enable flat optics: compact, thinner, easier fabrication and alignment
- Multifunctionality: single flat optical components can replace multiple standard components
- Flat Optics for a wide range of optical components (lenses, holograms, polarizers, phase plates, etc.) and applications: machine vision, biomed imaging, drones, polarimetry, polarization sensitive cameras
- Same foundries will manufacture camera sensor and lenses using same technology (deep-UV stepper) CMOS compatible flat optics platform for high volume markets: Examples: lenses in cell phone camera modules will be replaced by metalenses fabricated by

DUV lithography (same foundry that makes the sensor chip) Displays, wearable optics (augmented reality).

- Metasurfaces can generate arbitrary vector beams (structured light) well beyond the capabilities of SLM
- Importance of inverse design, co-design of hardware & software, impact of AI on optics
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